



2823

Docket No.: 005920 USA/FPS/MMCS/APC

PATENT/OFFICIAL

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :  
: SHANMUGASUNDRAM et al. :  
: Serial No. 09/943,383 : Group Art Unit: 2823 ✓  
: Filed: August 31, 2001 : Examiner: William D. Coleman  
For: IN SITU SENSOR BASED CONTROL OF SEMICONDUCTOR PROCESSING  
PROCEDURE

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Honorable Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

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to present to the Office the relevant facts and law regarding the appropriate status of such document.

No certification or fee is believed to be required. However, the Commissioner is hereby authorized to charge any additional fees should any be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

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**INFORMATION DISCLOSURE  
CITATION IN AN  
APPLICATION  
(PTO-1449)**



ATTY. DOCKET NO.  
005920  
USA/FPS/MMCS/APC

SERIAL NO.  
09/943,383

APPLICANT  
SHANMUGASUNDRAM et al.

FILING DATE  
August 31, 2001

GROUP  
2823

**U.S. PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,901,313	05/04/99	Wolf et al.			09/02/97
	6,002,989	12/14/99	Shiba et al.			04/01/97
	6,094,688	07/25/00	Mellen-Garnett et al.			03/12/98
	6,340,602	01/22/02	Johnson et al.			02/12/01
	6,345,288	02/05/02	Reed et al.			05/15/00
	6,368,879	04/09/02	Toprac			09/22/99
	US-2002/0107604	08/08/02	Riley et al.			12/06/00
	6,470,230	10/22/02	Toprac et al.			01/04/00
	6,482,660	11/19/02	Conchieri et al.			03/19/01
	6,567,717	05/20/03	Krivokapic et al.			01/19/00

**FOREIGN PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	WO 99/59200	11/18/99	WIPO			X	
	WO 01/52319	07/19/01	WIPO			X	

**OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)**

	Williams, Randy, Dadi Gudmundsson, Kevin Monahan, Raman Nurani, Meryl Stoller and J. George Shanthikumar. October 1999. "Optimized Sample Planning for Wafer Defect Inspection," <i>Semiconductor Manufacturing Conference Proceedings, 1999 IEEE International Symposium on Santa Clara, CA</i> . Piscataway, NJ. pp. 43 - 46.
	23 July 2003. Invitation to Pay Additional Fees and Communication Relating to the Results of the Partial International Search for PCT/US02/19116.
	01 August 2003. Written Opinion for PCT/US01/27406.
	20 August 2003. Written Opinion for PCT/US01/22833.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.